

Electronic Acknowledgement Receipt

EFS ID:	1254163
Application Number:	10748098
International Application Number:	
Confirmation Number:	6908
Title of Invention:	Reaction chamber for depositing thin film
First Named Inventor/Applicant Name:	Byung Chul Cho
Customer Number:	23413
Filer:	James J. Merrick/Shenita Carroll
Filer Authorized By:	James J. Merrick
Attorney Docket Number:	YPL-0070
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Application Type:	Utility

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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Amendment - After Non-Final Rejection	Response_to_OA_YPL-0070.pdf	1336249	no	12

Warnings:

Information:	Total Files Size (in bytes):	1336249
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<p>New Applications Under 35 U.S.C. 111 If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.</p>		
<p>National Stage of an International Application under 35 U.S.C. 371 If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.</p>		